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**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

(Use as many sheets as necessary)

Complete if Known

Application Number	10/773,796
Filing Date	02/06/2004
First Named Inventor	Veerasamy, Vijayen
Art Unit	1792
Examiner Name	Marianne Padgett
Attorney Docket Number	07-09-4750

Sheet 2 of 4

NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
/M.L.P./		Yamamoto, Takayuki, "Tribology of protective carbon films for thin film magnetic disk," Journal of the Surface Finishing Society of Japan, Vol. 44 (No. 10): 790-794, 1993. (no month) pages	
/M.L.P./		Bhushan, Bharat, et al., "Microscale mechanical and tribological characterization of hard amorphous carbon...", Surface and Coatings Technology, Vol. 76-77:655-669, 1995. (no month) pages	
		Bhushan, Bharat, et al., "Micro-scale tribological characterization...", International Conference on Metallurgical Coatings and Thin Films, G3.05, at 232, April 24-28, 1995.	
/M.L.P./		NSIC/ARPA Ultra-High Density Recording (UHDR) Project, Magnetic Disk Component Technical Progress Report, Quarter Ending December 31, 1994. pages 1-27	
		Cutiongco, Eric C., et al., "Tribological behavior of amorphous carbon nitride...", ASME/STLE Tribology Conference: republished in Journal of Tribology, vol. 118:543-548, 1996 (no month) presented October 1995	
		Khurshudov, Andrei, et al., "Microtribological characterization of carbon nitride coatings," Proceedings Int'l Tribology Conference, Yokohama, 1995. October	
	JJ Poon et al., ed.	Koidl, P., et al., "Plasma Deposition, Properties and Structure of Amorphous Hydrogenated Carbon Films," Materials Science Forum, Vols. 52-53, pp. 41-70, 1989. (no month)	
		McKenzie, D.R., et al., "Compressive-Stress-Induced Formation of Thin-Film Tetrahedral Amorphous Carbon," Physical Review Letters, Vol. 67(6):773-76, 1991. August	
		Cuomo, Jerome J., et al., "Vapor deposition processes for amorphous carbon films with sp ³ fractions approaching diamond," J. Appl. Phys. Vol. 70(3):1706-1711, 1991. August	
/M.L.P./		Schwan, J.S., et al., "Tetrahedral amorphous carbon films prepared by magnetron sputtering and dc ion plating," J. Appl. Phys. Vol. 79(30):1416-1422, 1996. February	

Examiner Signature	/Marianne Padgett/	Date Considered	02/12/2009
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/M.L.P./		Lossy, Richard, et al., "Properties of amorphous diamond films prepared by a filtered cathodic arc," Journal of Applied Physics, Vol. 77(9):4750-4756, 1995.	May
		Lossy, Richard, et al., "Filtered arc deposition of amorphous diamond," Appl. Phys. Lett. 61(2):171-173, 1992. July	
		Anders, Simone, et al., "Macroparticle-free thin films produced by an efficient vacuum arc deposition technique," J. Appl. Phys. 74(6):4239-4241, 4239, 1993. pages	September
		Sanders, David M., et al., "Coating Technology Based on the Vacuum Arc-A Review," IEEE Transactions on Plasma Science, Vol. 18(6):883-893, 1990. pages	December
		Lifshitz, Y., et al., "Growth mechanisms of DLC films from C+ ions: experimental studies," Diamond and Related Materials, Vol. 4:318-323, 1995. pages	(no month)
		Ager, Joel W., III, "Optical Characterization of Sputtered Carbon Films," IEEE Transactions on Magnetics, Vol. 29(1):259-263, 1993. January	
		Bhushan, Bharat, et al., <u>Handbook of Tribology: Materials, Coatings, and Surface Treatments</u> , 1991.(no month), excerpt pages 14.103-14.147 only	
		Franceschini, D.F., et al., "Internal stress reduction by nitrogen incorporation in hard amorphous carbon thin films," Appl. Phys. Lett. 60(26):3229-3231. June 1992	
		Jiang, Z., et al., "Nanotribological Evaluations of Hydrogenated Carbon Films as Thin as 5 nm on Magnetic Rigid Disks" IEEE Transactions on Magnetics, Vol. 31(6), 1995. November	
/M.L.P./		Iechika, et al., "Performance of hard DLC protective film prepared by PECVD method for thin film magnetic disk," IEEE Transactions on Magnetics, Vol. 30(6), 1994, pp.4134-4136 November	

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/M.L.P./		McKenzie & Veerasamy, "Hydrogen-free amorphous carbon preparation & properties", Diamond Rel. Mat., 3, 1994. (no month), pages 353-360	
/M.L.P./		Veerasamy, Vijayen S., "Tetrahedral Amorphous Carbon Deposition, Characterisation and Electronic Properties", Dissertation, Univ. of Cambridge, July 1994.	

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